

**PATENT** 

## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re: Davis Andrew McClure et al.

Group Art Unit: 2811

Serial No. 10/709,780 Filed: May 27, 2004

For: M

METHODS OF TREATING A SILICON CARBIDE

SUBSTRATE FOR IMPROVED EPITAXIAL DEPOSITION

AND RESULTING STRUCTURES AND DEVICES

October 22, 2004

Mail Stop Missing Parts Commissioner for Patents Alexandria, VA 22313-1450

## INFORMATION DISCLOSURE STATEMENT CITATION UNDER 37 C.F.R. 1.97

Sir:

Attached is a list of documents on Form PTO/SB/08. It is requested that the Examiner consider these documents and officially make them of record in accordance with the provisions of 37 C.F.R. § 1.97 and MPEP § 609.

This application is a divisional of U.S. Application No. 10/248,586, filed 01/30/2003. Because reference Nos. 1-22 were also cited in that case, copies are not being supplied herewith. Reference No. 23, a non-patent reference, was not previously cited and a copy is enclosed. Applicants will, of course, supply the Office with copies of any requested references.

Respectfully submitted,

Philip Summa Reg. No. 31,573

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Summa & Allan, P.A.

11610 North Community House Road

Suite 200

Charlotte, NC 28277-2162 Telephone: 704-945-6700 Facsimile: 704-945-6735

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## **CERTIFICATE OF MAILING**

I hereby certify that this correspondence is being deposited with the United States Postal Service with sufficient postage as first-class mail in an envelope addressed to: Mail Stop Missing Parts, Commissioner for Patents, Alexandria, VA 22313-1450 on October 22, 2004.

Philip Summa

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PTO/SB/08a (08-03)
Approved for use through 07/31/2006. OMB 0651-0031
U.S. Patent and Trademark Office; U.S. DEPARTMENT OF COMMERCE

nder the Paperwork Reduction Act of 1995, no persons are required to respond to a collection of information unless it contains a valid OMB control number.

## INFORMATION DISCLOSURE STATEMENT BY APPLICANT

 Complete if Known

 Application Number
 10/709,780

 Filing Date
 05/27/2004

 First Named Inventor
 Davis Andrew McClure et al.

 Art Unit
 2811

 Examiner Name

(Use as many sheets as necessary)

Substitute for form 1449A/PTO

Sheet 1 of 2 Attorney Docket Number 5000.238A

			U. S. PATENT		
Examiner Initials*	Cite No. <sup>1</sup>	Document Number  Number-Kind Code <sup>2</sup> (F known)	Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear
	1	<sup>US-</sup> 6,187,606 B1	02-13-2001	Edmond et al.	
***************************************	2	<sup>US-</sup> 6,120,600	09-19-2000	Edmond et al.	
	3	<sup>US-</sup> 5,523,589	06-04-1996	Edmond et al.	
	4	<sup>US-</sup> 5,900,647 A	05-04-1999	Inoguchi	
	5	<sup>US-</sup> 6,552,376 B1	04-22-2003	Koike et al.	
	6	<sup>US-</sup> 6,555,452 B2	04-29-2003	Nikolaev et al.	
	7	<sup>US-</sup> 6,632,694 B2	10-14-2003	Torvik	
	8	<sup>US-</sup> 3,629,011	12-21-1971	Tohi et al.	
	9	<sup>US-</sup> 2003/0006417 A1	01-09-2003	Klosowiak et al.	
	10	<sup>US-</sup> 2002/0031851 A1	03-14-2002	Linthicum et al.	
	11	<sup>US-</sup> 5,786,606 A	07-28-1998	Nishio et al.	
	12	<sup>US-</sup> 6,667,495 B2	12-23-2003	Friedrichs et al.	
	13	<sup>US-</sup> 5,273,933 A	12-28-1993	Hatano et al.	
	14	<sup>US-</sup> 6,232,244 B1	05-15-2001	lbok	
	15	<sup>US-</sup> 6,277,707 B1	08-21-2001	Lee et al.	WINDOWS AND CONTROL OF THE CONTROL O
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_	FOREIGN PATENT DOCUMENTS									
Examiner Initials*	Cite	Foreign Patent Document	Publication Date	Name of Patentee or	Pages, Columns, Lines,					
	No.¹	Country Code <sup>3</sup> Number <sup>4</sup> Kind Code <sup>5</sup> (# known)	MM-DD-YYYY	Applicant of Cited Document	Where Relevant Passages or Relevant Figures Appear	T <sup>5</sup>				
	16	PCT WO 00/79570 A2	12-28-2000	Advanced Tech. Materials						
	17	DE 199 44 144 A1	04-12-2001	Rossendorf Forschzent		~				
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Signature		Considered	
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\*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant. Applicant's unique citation designation number (optional). See Kinds Codes of USPTO Patent Documents at <a href="https://www.uspto.gov">www.uspto.gov</a> or MPEP 901.04. Enter Office that issued the document, by the two-letter code (WIPO Standard ST.3). For Japanese patent documents, the indication of the year of the reign of the Emperor must precede the serial number of the patent document. Skind of document by the appropriate symbols as indicated on the document under WIPO Standard ST.16 if possible. Applicant is to place a check mark here if English language Translation is attached.

This collection of information is required by 37 CFR 1.97 and 1.98. The information is required to obtain or retain a benefit by the public which is to file (and by the USPTO to process) an application. Confidentiality is governed by 35 U.S.C. 122 and 37 CFR 1.14. This collection is estimated to take 2 hours to complete, including gathering, preparing, and submitting the completed application form to the USPTO. Time will vary depending upon the individual case. Any comments on the amount of time you require to complete this form and/or suggestions for reducing this burden, should be sent to the Chief Information Officer, U.S. Patent and Trademark Office, U.S. Department of Commerce, P.O. Box 1450, Alexandria, VA 22313-1450. DO NOT SEND FEES OR COMPLETED FORMS TO THIS ADDRESS. SEND TO: Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450.

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1	Substitute to	r form 1449B/PTO			Complete if Known				
					Application Number	10/709,780			
	INFO	RMATION DI	SCLO	SURE	Filing Date	05/27/2004			
	STAT	EMENT BY A	APPLI	CANT	First Named Inventor	Davis Andrew McClure et al.			
					Art Unit	2811			
		(Use as many sheets as	necessary)		Examiner Name				
abla	Sheet	2	of	2	Attorney Docket Number	5000.238A	ノ		

NON PATENT LITERATURE DOCUMENTS							
Examiner Cite No.1		Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.					
	18	F.J. CAMPOS ET AL.; Confocal Micro-Raman Characterization of Lattice Damage in High Energy Aluminum Implanted 6H-SIC; Journal of Applied Physics; January 1, 1999; pgs. 99-104; Vol. 85, No. 1; American Institute of Physics, New York, US					
	19	M.B. SCOTT ET AL.; High temperature (500 degrees C) implantation study of P+ and N+ implanted epitaxial N-type 4H-SIC; Compound Semiconductors 1998, Proceedings of the 25th International Symposium on Compound Semiconductors; Nara, Japan, October 12-16, 1998; pages 763-768; Vol. NR. 162; Institute of Physics Conference Series, London					
	20	ISSEY OHTA ET AL.; An Ideal-Profile Implantation Process for GaAs Analog MMICs; Proceedings of the Gallium Arsenide Integrated Circuit Symposium, Grenelefe, Florida, October 28-30, 1986; pgs. 55-58; Vol. SYMP. 8; IEEE, New York, US					
3	21	W.M. DUNCAN ET AL.; A Single Step Selective Implantation Technology for Multiply Doped Layers Using Proximity Annealing; IEEE Electron Device Letters; December 1981; pgs. 309-311; Vol. EDL-2, No. 12; IEEE Inc., New York, US					
	22	H. J. HOVEL; Implant Profile Adjustment with GaA1As Caps; IBM Technical Disclosure Bulletin; February 1985; pgs. 5360-5361; Vol. 27, No. 9; IBM Corp., New York, US					
	23	S. K. LEe ET AL.; Electrical characterization of TiC ohmic contacts to aluminum ion implanted 4H-silicon carbide; Applied Physics Letters; Sept. 4, 2000; pp 1478-1480; Vol. 77, No. 10					
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Examiner	Date		
Signature	Considered		

<sup>\*</sup>EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

Applicant's unique citation designation number (optional). 2 Applicant is to place a check mark here if English language Translation is attached. This collection of information is required by 37 CFR 1.97 and 1.98. The information is required to obtain or retain a benefit by the public which is to file (and by the USPTO to process) an application. Confidentiality is governed by 35 U.S.C. 122 and 37 CFR 1.14. This collection is estimated to take 2 hours to complete, including gathering, preparing, and submitting the completed application form to the USPTO. Time will vary depending upon the individual case. Any comments on the amount of time you require to complete this form and/or suggestions for reducing this burden, should be sent to the Chief Information Officer, U.S. Patent and Trademark Office, U.S. Department of Commerce, P.O. Box 1450, Alexandria, VA 22313-1450. DO NOT SEND FEES OR COMPLETED FORMS TO THIS ADDRESS. SEND TO: Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450.